

Abstract

The present invention relates to a microstructured sensor, having at least:

- one measurement chip (2) in which there is formed a first measurement area (6) having a first measurement structure (9, 10, 12, 14) and a second measurement area (7) having a second measurement structure (9, 10, 12, 14), the measurement areas (6, 7) being offset to one another in a lateral direction (Y),
- one cap chip (4) that is fastened in vacuum-tight fashion to the measurement chip (2) in a connecting area (3),
- one intermediate space (5), formed between the measurement chip (2) and the cap chip (4), that is sealed outwardly by the connecting area (3) and in which the measurement areas (6, 7) are situated, and
- at least one contact area (20, 22, 30, 31; 29), formed on the measurement chip (2), and left exposed by the cap chip (4), for the contacting of the measurement chip (2).

The sensor can be in particular a gas sensor for measuring a gas concentration, or an acceleration sensor.

Figure 1